ELECTROLYTIC POLISHING APPARATUS, ELECTROLYTIC POLISHING METHOD, AND WAFER SUBJECT TO POLISHING. Inventor: Takeshi Nogami et al. Docket No. 075834.00509

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FIG. 1

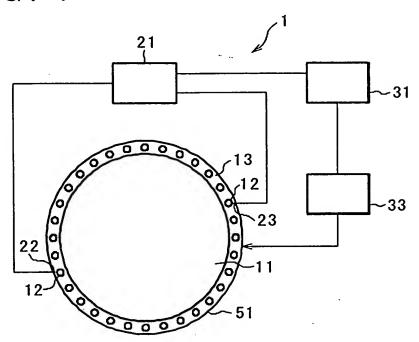
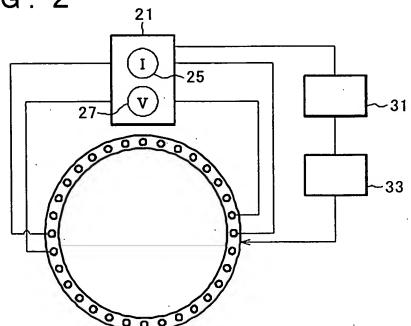


FIG. 2



ELECTROLYTIC POLISHING APPARATUS, ELECTROLYTIC POLISHING METHOD, AND WAFER SUBJECT TO POLISHING Inventor: Takeshi Nogami et al.

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FIG. 3

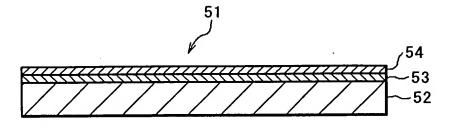
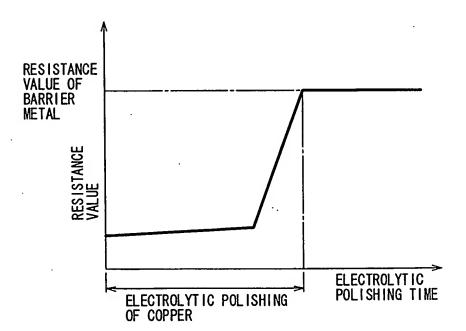


FIG. 4



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FIG. 5

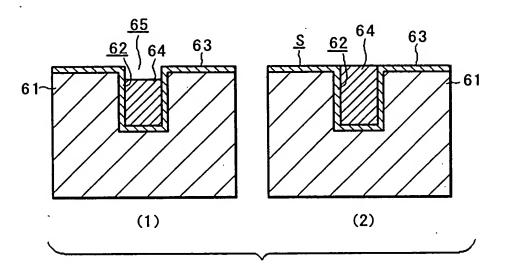


FIG. 6

